



ELECTRONIC INFORMATION DISCLOSURE STATEMENT

Electronic Version v18
Stylesheet Version v18.0

Title of
Invention

SOLVENT FREE PHOTORESIST STRIP AND RESIDUE
REMOVAL PROCESSING FOR POST ETCHING OF LOW-
K FILMS

Application Number: 10/761122



Confirmation Number: 8790

First Named Applicant: HUONG NGUYEN

Attorney Docket Number: AMAT5735C1

Search string: ('6214728 or 6130166 or 6124213 or 6074569
or 6062237 or 6046115 or 6043004 or 6037255
or 6030901 or 6024045 or 5811358 or 5681780
or 5660682 or 4357203 or 4028155).pn.

US Patent Documents

Note: Applicant is not required to submit a paper copy of cited US Patent Documents

init	Cite.No.	Patent No.	Date	Patentee	Kind	Class	Subclass
<input checked="" type="checkbox"/>	1	6214728	2001-04-10	CHAN, ET AL.			
<input type="checkbox"/>	2	6130166	2001-10-10	YEH			
<input type="checkbox"/>	3	6124213	2000-09-26	USAMI, ET AL.			
<input type="checkbox"/>	4	6074569	2000-06-13	KIZILOGLU, ET AL.			
<input type="checkbox"/>	5	6062237	2000-05-16	BROWN, ET AL.			
<input type="checkbox"/>	6	6046115	2000-04-04	MOLLOY, ET AL.			
<input type="checkbox"/>	7	6043004	2000-03-28	KURIMOTO			
<input type="checkbox"/>	8	6037255	2000-03-14	HUSSEIN, ET AL.			
<input type="checkbox"/>	9	6030901	2000-02-29	HOPPER, ET AL.			
<input type="checkbox"/>	10	6024045	2000-02-15	KIKUCHI, ET AL.			
<input type="checkbox"/>	11	5811358	1998-09-22	TSENG, ET AL.			
<input type="checkbox"/>	12	5681780	1997-10-28	MIHARA, ET AL.			
<input type="checkbox"/>	13	5660682	1997-08-27	ZHAO, ET AL.			
<input checked="" type="checkbox"/>	14	4357203	1982-11-02	ZELEZ			
<input checked="" type="checkbox"/>	15	4028155	1977-06-07	JACOB			

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R. Duda

7/7/06

Comments